Customer No.: 31561 Application No.: 10/710,785 Docket No.: 12432-US-PA

AMENDMENTS

To the Claims:

1. (original) A method for fabricating a thin film of an organic electroluminescent device, adapted to form a patterned thin film layer on a substrate, the method comprising: providing a mask;

aligning the substrate and the mask under non-vacuum environment, fastening the mask with the substrate; and

transferring the fastened substrate and mask into vacuum environment, forming the patterned thin film layer by the mask.

- 2. (withdrawn) The method for fabricating a thin film of an organic electroluminescent device of claim 1, wherein the non-vacuum environment is atmosphere environment.
- 3. (original) The method for fabricating a thin film of an organic electroluminescent device claim 1, wherein the non-vacuum environment is environment having water and/or oxygen concentration about from 0.1 to 100 ppm.
- 4. (original) The method for fabricating a thin film of an organic electroluminescent device of claim 1, wherein the patterned thin film layer is formed by vapor deposition or sputtering.
- 5. (original) The method for fabricating a thin film of an organic electroluminescent device of claim 1, wherein the step of forming the patterned thin film layer comprises:

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forming a first conductive layer on the substrate by using the mask; and forming a second conductive on the first conductive layer by using the mask.

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6. (original) A method for fabricating a thin film of an organic electroluminescent

device, adapted to form a patterned thin film layer on a substrate, the method comprising:

providing a film-forming apparatus, comprising at least one vacuum chamber and at least one non-vacuum chamber;

aligning the substrate and the mask in the non-vacuum chamber, fastening the mask with the substrate; and

transferring the fastened substrate and mask into the vacuum chamber, forming the patterned thin film layer by the mask.

- 7. (withdrawn) The method for fabricating a thin film of an organic electroluminescent device of claim 6, wherein the non-vacuum environment is atmosphere environment.
- 8. (original) The method for fabricating a thin film of an organic electroluminescent device of claim 6, wherein the non-vacuum environment is environment having water and/or oxygen concentration about from 0.1 to 100 ppm.
- 9. (original) The method for fabricating a thin film of an organic electroluminescent device of claim 6, wherein the patterned thin film layer is formed by vapor deposition or sputtering.

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10. (original) The method for fabricating a thin film of an organic electroluminescent device of claim 6, wherein the step of forming the patterned thin film layer comprises:

forming a first conductive layer on the substrate by using the mask; and forming a second conductive on the first conductive layer by using the mask.

Claims 11-32 (canceled)